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mounting on said work station mounting surface, said base having alignment holes, said work station surface including alignment pins for insertion into said alignment holes for aligning said first channel with said first opening in said work station mounting surface and said second channel with said second opening in said work station mounting surface.

7. A semiconductor processing system, comprising:

a wafer storage cassette, including:

a plurality of walls surrounding a chamber for containing semiconductor wafers, said plurality of walls including a base for mounting on a work surface of a work station, an upper wall, and side wall means for connecting said base and said upper wall, said base including first and second ports, said side wall means including a first opening adjacent said base and a second opening opposed to said first opening and adjacent said upper wall;

a first channel connecting said first opening with said first port;

a second channel connecting said second opening with said second port;

a first valve in said first channel; and

a second valve in said second channel.

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8. The semiconductor processing system of claim 7, further including:

a first baffle within said chamber, said first baffle adjacent and substantially perpendicular to said first opening, said first baffle located below the semiconductor wafers and extending from one of said plurality of walls; and

a second baffle within said chamber, said second baffle adjacent said second opening, said second baffle having a first portion surrounding at least some of the semiconductor wafers and extending above the semiconductor wafers.

9. The semiconductor processing system of claim 7, further including:

a work station having a mounting surface, said mounting surface having a first port for interfacing with said first port in said base and a second port for interfacing with said second port in said base.

10. The semiconductor processing system of claim 9, said work station further including:

a first line connected to said first port in said mounting surface;

a second line connected to said second port in said mounting surface;

a third valve in said first line; and

a fourth valve in said second line.

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